plurality of metal layers. In an exemplary process of forming the first and second connection vias 170C1 and 170C2, a plurality of plating processes may be performed to form the plurality of metal layers.

[0171] Thereafter, a conductive layer (not shown) may be formed on the second insulating layer 154 and the first and second connection vias 170C1 and 170C2 and patterned, thereby forming first and second conductive pads 170P1 and 170P2 that are electrically connected to the first and second connection vias 170C1 and 170C2, respectively.

[0172] In another case, the formation of the first and second conductive pads 170P1 and 170P2 may include forming a conductive layer (not shown) on the second insulating layer 154 during the formation of the first and second conductive vias 170C1 and 170C2 and removing the conductive layer to leave only portions of the conductive layer located on the second insulating layer 154 around the first and second via holes 170H1 and 170H2.

[0173] A top surface of the heat spreading layer 160 may be exposed by removing the second insulating layer 154 from the active pixel sensor area APS.

[0174] Referring to FIG. 22, a passivation layer 180 may be formed on the first and second conductive pads 170P1 and 170P2, the second insulating layer 154, and the heat spreading layer 160. The passivation layer 180 may be partially removed to expose top surfaces of the first and second conductive pads 170P1 and 170P2 in the first pad area PA and expose the top surface of the heat spreading layer 160 in the active pixel sensor area APS.

[0175] A color filter layer 182 and a microlens 184 may be sequentially formed on the heat spreading layer 160.

[0176] In some embodiments, during the formation of the color filter layer 182 and the microlens 184, the top surfaces of the first and second conductive pads 170P1 and 170P2 may be covered with a protection layer (not shown), a final passivation layer (not shown) may be formed on the color filter layer 182 and the microlens 184, and unnecessary layers covering the first and second conductive pads 170P1 and 170P2 may be removed to expose the first and second conductive pads 170P1 and 170P2 again.

[0177] Subsequently, a support substrate 260 may be adhered to the back surface 110B of the first substrate 110 on which the color filter layer 182 and the microlens 184 are formed. An adhesive member 262 may be interposed between the first substrate 110 and the support substrate 260 so that the support substrate 260 may be adhered to the back surface 110B of the first substrate 110.

[0178] A stacked structure of the first substrate 110 to which the support substrate 260 is adhered and the second substrate 210 may be turned upside down so that the back surface 210B of the second substrate 210 may face upward.

[0179] A thinning process may be performed to remove a desired (or, alternatively, predetermined) thickness from the back surface 210B of the second substrate 210. For example, the thinning process may be performed by using at least one of a CMP process, a BGR process, or an RIE process.

[0180] In the image sensor 100E, since the heat spreading layer 160 is located on the entire area of the active pixel sensor area APS, heat generated during operations of the circuits 20 (refer to FIG. 2) included in the circuit area CA may be uniformly distributed throughout the entire area of the sensor array area SA. Accordingly, non-uniform generation of dark current may be reduced and/or prevented in the sensor array area SA.

[0181] FIG. 23 is a block diagram of a system 1000 including an image sensor according to some example embodiments.

[0182] Referring to FIG. 23, the system 1000 may be any one of a computing system, a camera system, a camcorder, a portable phone, a scanner, a car navigation, a video phone, a security system, a game console, a medical micro-camera, a robot, or a motion detection system, which may utilize image data.

[0183] The system 1000 may include a central processing unit (CPU) (or a processor) 1100, a non-volatile memory 1200, an image sensor 1300, an input/output (I/O) device 1400, and a random access memory (RAM) 1500. The CPU 1100 may communicate with the non-volatile memory 1200, the image sensor 1300, the I/O device 1400, and the RAM 1500 via a bus 1600. The image sensor 1300 may be embodied by at least one of the image sensors 10, 10A, 100, 100A, 100B, 100C, 100D, 100E, 100F, 100G, 100H, and 1001 described above with reference to FIGS. 1 to 22 according to some example embodiments or combined with the CPU 1100 into a single semiconductor package.

[0184] FIG. 24 is a block diagram of an electronic system 2000 and interface including an image sensor according to some example embodiments.

[0185] Referring to FIG. 24, the electronic system 2000 may be embodied by a data processing device (e.g., a mobile phone, a personal digital assistant (PDA), a portable multimedia player (PMP), or a smartphone) capable of using or supporting a mobile industry processor interface (MIPI). The electronic system 2000 may include an application processor 2010, an image sensor 2040, and a display 2050. [0186] A camera serial interface (CSI) host 2012 provided in the application processor 2010 may serial-communicate with a CSI device 2041 of the image sensor 2040 via a CSI. In this case, an optical deserializer is provided in the CSI host 2012, and an optical serializer may be provided in the CSI device 2041. The image sensor 2040 may include at least one of the image sensors 10, 10A, 100, 100A, 100B, 100C, 100D, 100E, 100F, 100G, 100H, and 1001 described with reference to FIGS. 1 to 22, according to some example embodiments.

[0187] A display serial interface (DSI) host 2011 provided in the application processor 2010 may serial-communicate with a DSI device 2051 of the display 2050 via a DSI. In this case, for example, an optical serializer may be provided in the DSI host 2011, and an optical deserializer may be provided in the DSI device 2051.

[0188] The electronic system 2000 may further include an RF chip 2060 capable of communicating with the application processor 2010. A PHY 2013 of the electronic system 2000 may exchange data with a PHY 2061 of the RF chip 2060 based on MIPI DigRF.

[0189] The electronic system 2000 may further include a global positioning system (GPS) 2020, a storage 2070, a mike 2080, a dynamic random access memory (DRAM) 2085, and a speaker 2090. The electronic system 2000 may perform communication operations by using a worldwide interoperability for microwave access (WiMAX) 2030, a wireless local area network (WLAN) 2100, and an ultrawideband (UWB) 2110.

[0190] It should be understood that example embodiments described herein should be considered in a descriptive sense only and not for purposes of limitation. Descriptions of features or aspects within each device or method according